

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant :	Satoru Okamoto	Art Unit :	1792
Serial No. :	10/689,617	Examiner :	Mahmoud Dahimene
Filed :	October 22, 2003	Conf. No. :	4799
Title :	METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE		

MAIL STOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450


NOTICE OF APPEAL

Applicant hereby appeals to the Board of Patent Appeals and Interferences from the action dated August 3, 2009, finally rejecting claims 1-95.

The amount of \$540 for the appeal fees are being paid concurrently herewith on the Electronic Filing System (EFS) by way of Deposit Account authorization. Please apply any other charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: 2 November 2009



Roberto J. Devoto
Reg. No. 55,108

Fish & Richardson P.C.
1425 K Street, N.W.
11th Floor
Washington, DC 20005-3500
Telephone: (202) 783-5070
Facsimile: (877) 769-7945